

L Number	Hits	Search Text	DB	Time stamp
1	23790	(SiGe (silicon near5 germanium))	USPAT; US-PGPUB	2004/04/27 11:06
4	5758	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 11:01
5	3377	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 10:50
6	2515	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 10:49
7	5758	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) )	USPAT; US-PGPUB	2004/04/27 10:49
9	776	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) with (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 11:03
10	1510	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) same (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 10:51
11	191	((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) near (SiGe (silicon near5 germanium)))	USPAT; US-PGPUB	2004/04/27 10:51

12	1510	<p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) with (SiGe (silicon near5 germanium))) )</p> <p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) same (SiGe (silicon near5 germanium))) )</p> <p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) near (SiGe (silicon near5 germanium))) )</p>	USPAT; US-PGPUB	2004/04/27 10:51
13	670	<p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) with (SiGe (silicon near5 germanium))) )</p> <p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) same (SiGe (silicon near5 germanium))) )</p> <p>((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) near (SiGe (silicon near5 germanium))) ) and ((bond\$3 transfer\$5)</p>	USPAT; US-PGPUB	2004/04/27 11:04

14	604	(((((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) same (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) near (SiGe (silicon near5 germanium))) ) and (bond\$3 transfer\$5)) and (insulat\$3 dielectric)	USPAT; US-PGPUB	2004/04/27 10:52
15	32	(((((((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) same (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) same (SiGe (silicon near5 germanium))) ) ((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) with (SiGe (silicon near5 germanium))) ) (((SiGe (silicon near5 germanium)) ) and ((implant\$3 dop\$4) near5 (SiGe (silicon near5 germanium))) ) and ((pattern\$4 etch\$3) near (SiGe (silicon near5 germanium))) ) and (bond\$3 transfer\$5)) and (insulat\$3 dielectric)) and (smart near5 cut)	USPAT; US-PGPUB	2004/04/27 10:53
16	8107	(SiGe (silicon near5 germanium))	EPO; JPO; DERWENT; IBM_TDB	2004/04/27 11:05
17	1214	((SiGe (silicon near5 germanium)) ) and (implant\$3 dop\$4)	EPO; JPO; DERWENT; IBM_TDB	2004/04/27 11:02
18	225	(((SiGe (silicon near5 germanium)) ) and (implant\$3 dop\$4)) and (pattern\$4 etch\$3)	EPO; JPO; DERWENT; IBM_TDB	2004/04/27 11:04
19	11	((((SiGe (silicon near5 germanium)) ) and (implant\$3 dop\$4)) and (pattern\$4 etch\$3) ) and (bond\$3 transfer\$5)	EPO; JPO; DERWENT; IBM_TDB	2004/04/27 11:04

20	0	((SiGe (silicon near5 germanium)) ) and (smart near5 cut)	EPO; JPO; DERWENT; IBM_TDB	2004/04/27 11:05
21	1	(SiGe (silicon near5 germanium)) near100 (transfer\$4 bond\$3) near100 (etch\$3 pattern\$4) near100 (inulat\$3 dielectric)	USPAT; US-PGPUB	2004/04/27 11:08
22	48	(SiGe (silicon near5 germanium)) same (transfer\$4 bond\$3) same (etch\$3 pattern\$4) same (inulat\$3 dielectric)	USPAT; US-PGPUB	2004/04/27 11:08